



The Materials Metrology™ Company

Press Release

## ReVera Announces the VeraFlex™ Materials Metrology™ System

Flexible capabilities enable semiconductor producers to measure, monitor and control critical properties of emerging materials for 65 nm, 45 nm and beyond

---

**Sunnyvale, Calif., December 1, 2005** – ReVera Incorporated, the materials metrology company, today announced its new VeraFlex metrology system. Built on the capabilities of ReVera's widely adopted RVX 1000 system, VeraFlex addresses the increasing demands for materials metrology from development through production on product and monitor wafers. VeraFlex's broad measurement capabilities – including thickness, composition, profile, bonding states, interface quality and surface condition – provide a flexible solution for a wide range of emerging materials metrology requirements.

VeraFlex is immediately available and has been ordered by and installed at multiple leading edge semiconductor manufacturers for use in both development and production.

"Our customers are facing a critical new challenge – the introduction of multiple new materials and processes for sub 65 nm nodes," noted David Ring, President and CEO of ReVera. "In fact, one leading semiconductor manufacturer recently stated that future semiconductor performance and feature improvements were not going to come in the form of scaling, but rather through materials innovations. Deploying these new materials requires versatile materials metrology that can provide much more than thickness information. Today, other critical information is required such as composition, profile, bonding states, interface quality and surface condition across multiple applications. The VeraFlex materials metrology system does just that, offering a flexible platform that provides the breadth of capabilities needed for development, and exceeding the reliability, automation and throughput requirements of the semiconductor production environment."

Ring continued, "VeraFlex leverages the experience we gained with our successful RVX 1000 metrology system. The RVX 1000 enabled ReVera to enter the materials metrology marketplace with a functional and reliable system that addresses changes in dielectric layers. It also allowed us to work closely with leading semiconductor manufacturers to understand their critical challenges for 65 nm, 45 nm and beyond. We used that customer experience to drive our development, and VeraFlex is the result – a flexible and powerful system that enables customers to measure, monitor and control critical materials properties, thereby solving a wide array of emerging semiconductor measurement and processing problems."

ReVera will highlight its VeraFlex materials metrology system at SEMICON Japan December 7-9, 2005. Visit ReVera at the Noah Corporation booth # 3A-704 to learn more.

### **About ReVera**

ReVera Incorporated is the leading provider of materials metrology solutions for advanced semiconductor processing. Its products allow device manufacturers to measure, monitor and control critical materials properties, enabling them to rapidly integrate and manage the new materials required for 65 nm, 45 nm and beyond. ReVera systems are proven in production in a broad range of applications, and are backed by a global network of applications, field service, sales and logistics personnel. ReVera was established in 2004 as a management-led spin-out from Physical Electronics and its wholly owned subsidiary, Charles Evans and Associates.